



Attorney's Docket No.: 042390P8276

Patent

#9/A
no
11/26/02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Anne E. Miller et al.

U.S. Serial No: 09/715,282

Filed: November 16, 2000

Examiner: Chen, Kin Chan

Art Unit: 1765

For: SLURRY AND METHOD FOR
CHEMICAL MECHANICAL POLISHING
OF COPPER

Assistant Commissioner for Patents
and Trademarks
Washington, D.C. 20231

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AMENDMENT AND RESPONSE

Dear Sir:

This is in response to the Office Action mailed August 12, 2002. Applicant respectfully requests the Examiner to enter the following amendments and consider the following remarks.

FIRST CLASS CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage in an envelope addressed to the Assistant Commissioner of Patents, Washington, D.C. 20231

on November 12, 2002

Date of Deposit

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